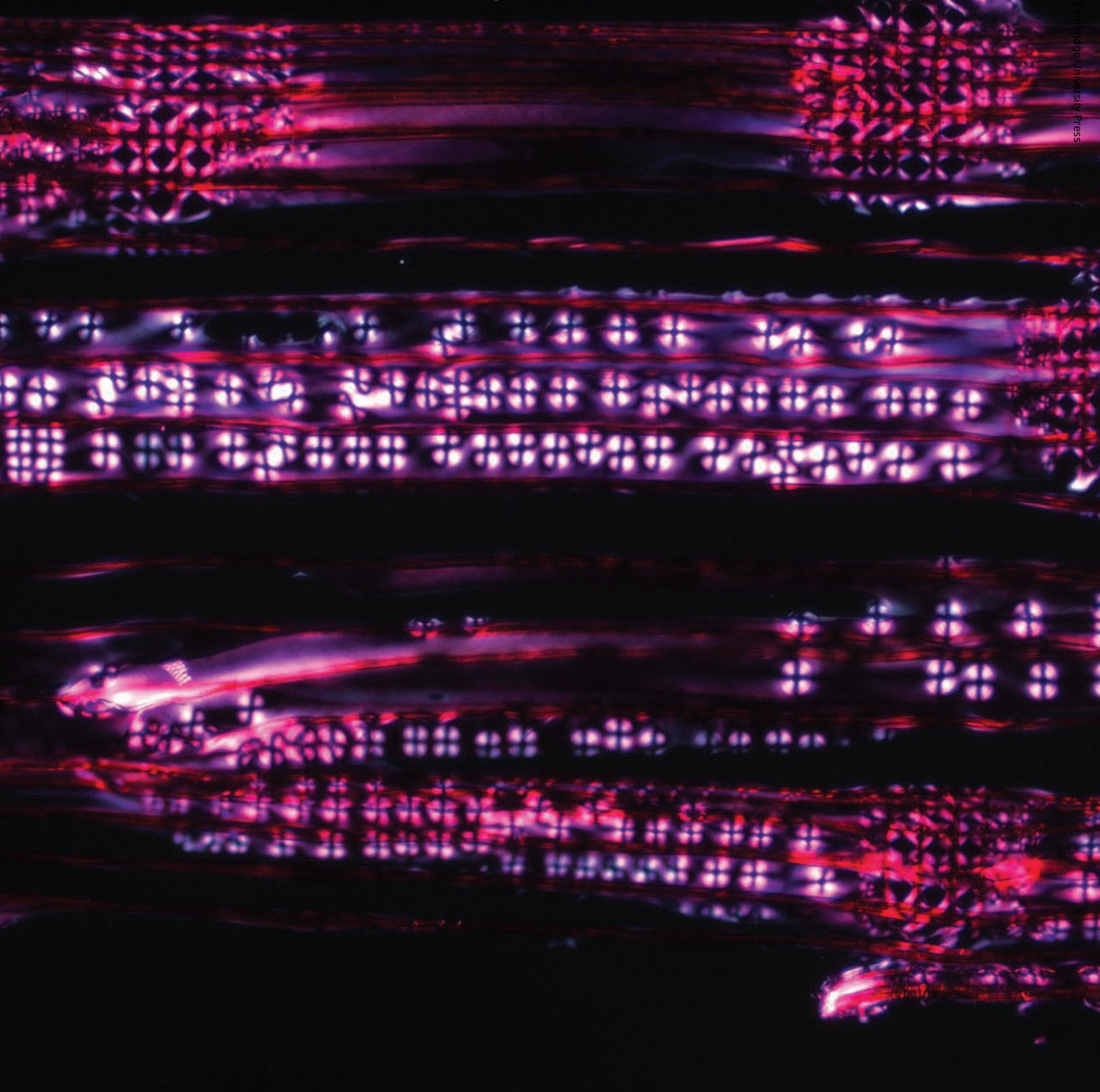


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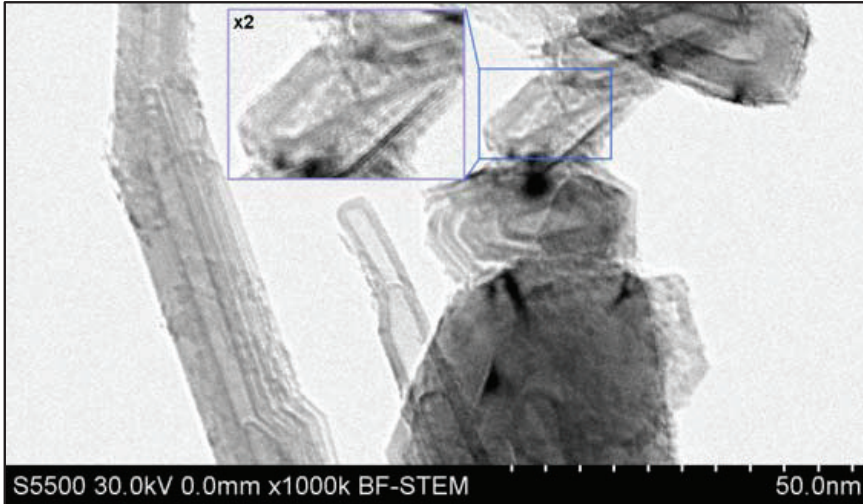
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The Ultimate in Resolution.

Hitachi S-5500

In-lens Field Emission Scanning Electron Microscope



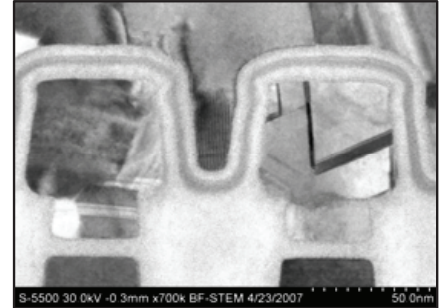
Fringes of MWCNT in STEM

The Hitachi S-5500 is a dedicated ultra-high resolution In-lens FE-SEM for leading edge research and development of nanotechnologies. The patented in-lens technology provides the ultimate performance of 0.4nm guaranteed imaging resolution.

The S-5500 is equipped with a shielding system for reduced EMI and acoustic interferences. These improvements with a completely dry vacuum system ensures Hitachi's high-resolution guarantee for the life of the instrument.

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NAND double-gate cross-section in STEM



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